Rules for Optical Testing

H. Philip Stahl, PhD

NASA Marshall Space Flight Center, Huntsville, AL

Rules for Optical Metrology

Based on 30 years of optical testing experience, a lot of mistakes, a lot of learning and a lot of experience,

I have defined seven guiding principles for optical testing – regardless of how small or how large the optical testing or metrology task

GUIDING PRINCIPLES
1. Fully Understand the Task
2. Develop an Error Budget
3. Continuous Metrology Coverage
4. Know where you are
5. 'Test like you fly'
6. Independent Cross-Checks
7. Understand All Anomalies

These rules have been applied with great success to the in-process optical testing and final specification compliance testing of the JWST mirrors.

Rule #1: Fully Understand the Task

Make sure that you fully understand your task:

who is your customer;

what parameters do you need to quantify;

to what level of uncertainty you must know their value; and

who is your manufacturing interface?

Before accepting any testing task, study your customer's requirements and understand how they relate to the final system application.

Then summarize all requirements into a simple table which can be shared with your customer and your manufacturing methods engineer.

Make sure that your customer agrees that what you will quantify satisfies their requirements and the manufacturing methods engineer agrees that they can make the part based upon the data you will be providing.

JWST is Customer making Segmented PM
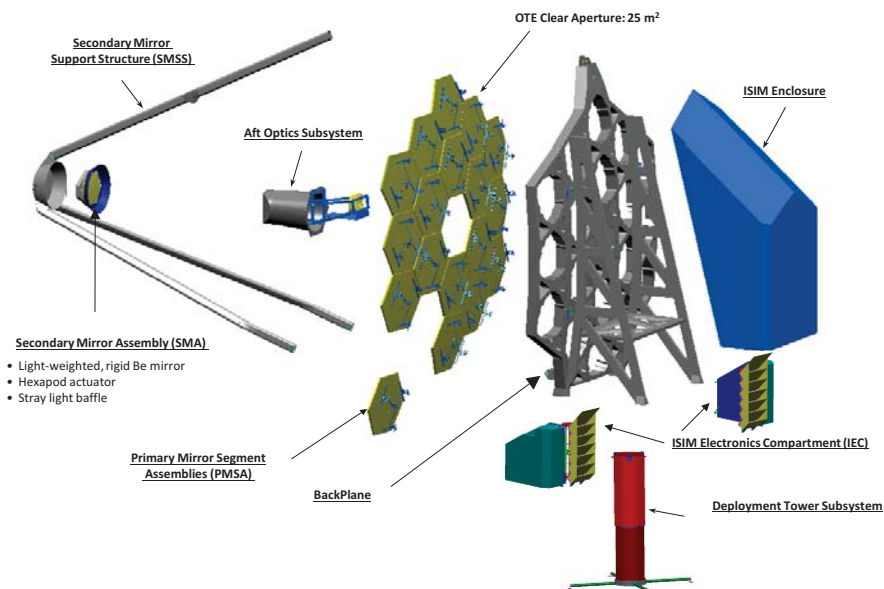
JWST Optical Testing Needs

The principle JWST optical testing needs include:

Optical Component Assemblies

Primary Mirror Segment Assembly (PMSA)	18 + 3 spares
Secondary Mirror Assembly (SMA)	1 + 1 spare
Tertiary Mirror Assembly (TMA)	1

Observatory Elements

Primary Mirror Assembly (PMA)

Optical Telescope Element (OTE)

Additionally, there are multiple other optics such as the fine steering mirror and various instrument optical components.
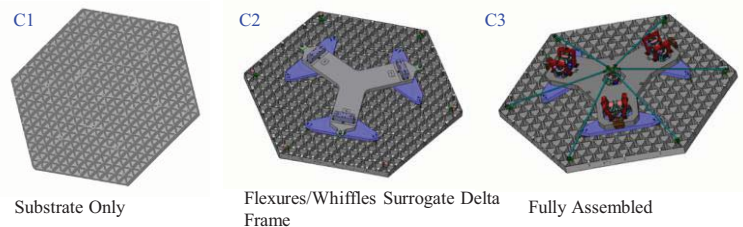
Optical Component Configurations

There are 3 mirror configuration 'states':

Configuration 1 = Substrate Only

Configuration 2 = Flight Flexures & Whiffle and Surrogate Delta Frame

Configuration 3 = Flight

C1   C2   C3

Substrate Only   Flexures/Whiffles Surrogate Delta Frame   Fully Assembled

JWST Optical Component Specifications

All Components have Cryogenic Performance Specifications

Since components are fabricated at Ambient it is necessary to Cryo-Null Figure, i.e. compensate for ambient to cryo changes

All Components have:

an Initial Requirement which must be met before Cryo-Testing

a Final Post Cryo-Null Figuring Requirement, and

a Final Cryogenic Performance Requirement

Segment Fabrication Requirements & Tolerances

Parameter	Specification	Tolerance	Units	Comments
Requirements for initial figuring				
Clear Aperture (based on Edge Specification)	1.4776	Minimum	mm^2	*Different for 3 segments
Scratch-Dig	80-50	Maximum		
Conic Constant	-0.99666	+/- 0.0010		
Radius of Curvature	15899.915	+/- 1	mm	
Prescription Alignment Error				
Decenter	*	≤ 0.35	mm	*Different for 3 segments
Clocking	0	≤ 0.35	mrad	
Piston	N/A			Measure only, no requirement
Tilt	N/A			Measure only, no requirement
Total Surface Figure Error:				
Low/Mid Frequency (≥222 mm/cycle)	150	Maximum	nm rms	
High Frequency (222 to 0.08mm/cycle)	20	Maximum	nm rms	
Slope Error	25	Maximum	μrad	
Requirements for cryo-null figuring				
Clear Aperture (based on Edge Specification)	1.4776	Minimum	mm^2	*Different for 3 segments
Scratch-Dig	80-50	Maximum		
Conic Constant	-0.99666	+/- 0.0005		
Radius of Curvature	*	+/- 0.10	mm	*Radius value supplied
Prescription Alignment Error				
Decenter	*	≤ 0.35	mm	* Decenter value supplied
Clocking	0	≤ 0.35	mrad	
Piston	N/A			Measure only, no requirement
Tilt	N/A			Measure only, no requirement
Total Surface Figure Error:				
Low/Mid Frequency (≥222 mm/cycle)	20	Maximum	nm rms	Relative to cryo-target map
High Frequency (222 to 0.08mm/cycle)	7	Maximum	nm rms	Relative to cryo-target map
PSD Spike Requirement	Spike Limit			
Surface Roughness	4	Maximum	nm rms	

Metrology Plan for Each Requirement

Parameter	Spec	Tol	Units	Verification	Validation
Clear Aperture (Edge Specification)	1.4776 (5)	Min (Max)	mm^2 (mm)	Measure edges at ambient using Tinsley HS Interferometer	Measure area at cryo using XRCF CoC Interferometer
Scratch-Dig	80-50	Max		Ambient Visual Inspection	Independent Visual
Conic Constant	-0.99666	+/- 0.0005		Measured at cryo and defined by null geometry for XRCF CGH CoC test	Ambient test at Tinsley, compare CGH CoC test with auto-collimation test
Radius of Curvature	*	+/- 0.15	mm	Set at XRCF using ADM	ROCO Comparison
Prescription Alignment Error					
Decenter	*	≤ 0.35	mm	Cryogenic test at XRCF, defined by residual wavefront error relative to CGH CoC test and fiducial alignment	Ambient test at Tinsley, compare CGH CoC test with auto-collimation test
Clocking	0	≤ 0.35	mrad		
Piston	N/A			Ambient CMM measurement at AXSYS	Ambient CMM measurement at Tinsley
Tilt	N/A				
Total Surface Figure Error:					
Low/Mid Frequency	20	Max	nm rms	Cryo-Test at XRCF	Cryo-Test at JSC
High Frequency	7	Max	nm rms		
Surface Roughness	4	Max	nm rms	Ambient Chapman measurement at Tinsley	NONE

Lesson Learned Example

A simple example of how not 'fully understanding the task' causes trouble is Zernike polynomial coefficients.

Optical designers use Zernike coefficients to specify components and metrologists use Zernike coefficients to describe surface shape. But, which Zernike coefficients? Also, PV or RMS?

Table 1. Zernike Polynomial Coefficient Index (first 8 coefficients only)					
Description	Polynomial	ISO	FRINGE	Born & Wolfe	Kodak
Piston	1	0	1	1	0
X-Tilt	$r \cos\theta$	1	2	2	1
Y-Tilt	$r \sin\theta$	2	3	3	2
Power	$2r^2 - 1$	3	4	5	3
X-Astigmatism	$r^2 \cos2\theta$	4	5	4	4
Y-Astigmatism	$r^2 \sin2\theta$	5	6	6	5
X-Coma	$(3r^2 - 2) r \cos\theta$	6	7	8	6
Y-Coma	$(3r^2 - 2) r \sin\theta$	7	8	9	7
Spherical	$6r^4 - 6r^2 + 1$	8	9	13	10

Design software typically use B&W while Interferometer software typically use Fringe. Orders are different.

Lesson Learned Example

Also, some designers and fabricators use PV Zernike Coefficients and some use RMS.

Optical designers use Zernike coefficients to specify components and metrologists use Zernike coefficients to describe surface shape. But, which Zernike coefficients? Also, PV or RMS?

Table 1. Zernike Polynomial Coefficient Index (first 8 coefficients only)						
Description	Polynomial	ISO	FRINGE	Born & Wolfe	Kodak	RMS to PV Ratio
Piston	1	0	1	1	0	1
X-Tilt	$r \cos\theta$	1	2	2	1	½
Y-Tilt	$r \sin\theta$	2	3	3	2	½
Power	$2r^2 - 1$	3	4	5	3	1/sqrt(3)
X-Astigmatism	$r^2 \cos2\theta$	4	5	4	4	1/sqrt(6)
Y-Astigmatism	$r^2 \sin2\theta$	5	6	6	5	1/sqrt(6)
X-Coma	$(3r^2 - 2) \, r \cos\theta$	6	7	8	6	1/sqrt(8)
Y-Coma	$(3r^2 - 2) \, r \sin\theta$	7	8	9	7	1/sqrt(8)
Spherical	$6r^4 - 6r^2 + 1$	8	9	13	10	1/sqrt(5)

Rule #2: Develop an Error Budget

Develop an error budget for every specification & tolerance.

Error budget predicts test accuracy and reproducibility (not repeatability) of the metrology tools.

> Reproducibility is the ability of 'independent' measurement executions to achieve the same answer, e.g. take down and re-set a test.

All elements of error budget must be certified by absolute calibration and verified by independent test.

An error budget has multiple functions.
> Convinces your customer that you can actually measure the required parameters to the required tolerances;
> Defines which test conditions have the greatest impact on test uncertainty;
> Provides a tool for monitoring the test process.

If the variability in the test data exceeds the error budget prediction, then you must stop and understand why.

Error Budget Contingency

An Error Budget MUST have Contingency Reserve.

No matter how much one thinks about every potential contingency risk or how careful one executes, errors happen.

Three examples of mirrors fabricated according to an error budget – which were in fact better than the error budget until an error occurred. Because of Reserve, they all met their final requirement specification.

On Spitzer, the assembled telescope was well below its requirement until the shake test. A bolt hole which was not deep enough introduced forces which bent the Primary Mirror (by approx 1/3rd of its requirement). But, the total system still met spec.

On JWST, as the primary mirror segment fabrication process improved, the segments were greatly below their requirement. But, an incorrect calibration file was used on two PMSAs resulting in residual excess power (of approx 1/3rd of its figure requirement). But, the primary mirror still met spec.

On JWST, the secondary mirror's ambient surface figure error was well below its requirement. But, metal tape used to attach the thermal couples to the secondary mirror during its cryo test introduced a residual error into the cryo-hit map (of approx 1/3rd of its figure requirement). But, the primary mirror still met spec.

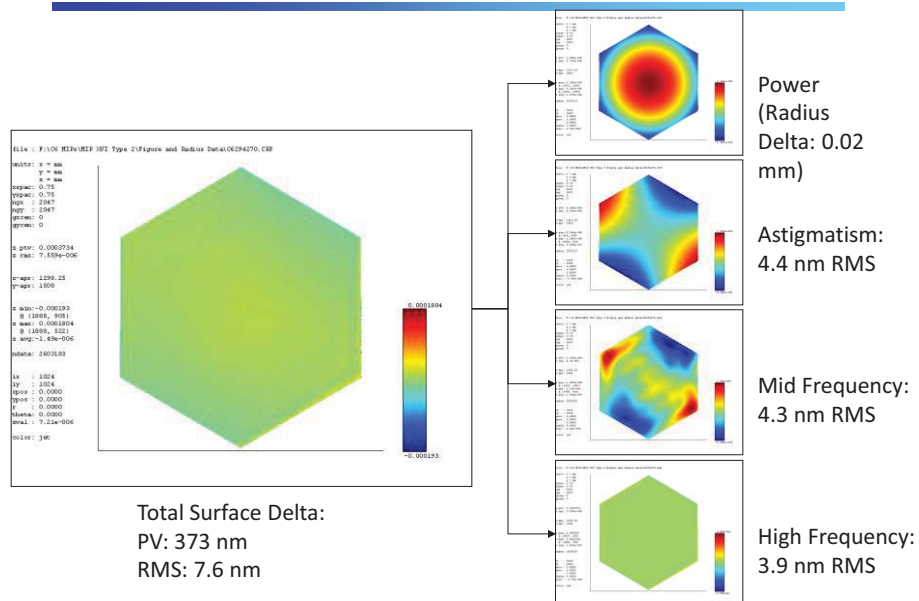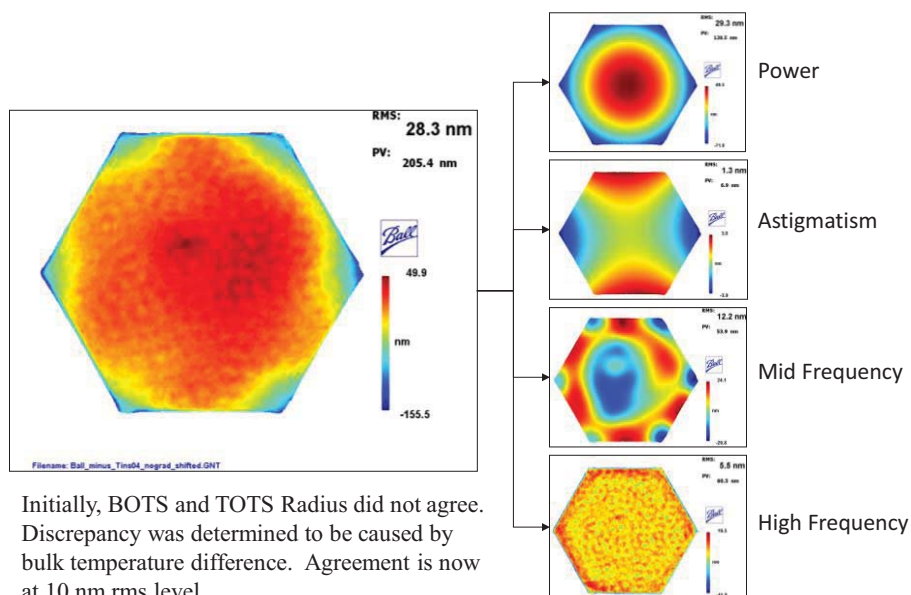A good value for Error Budget Reserve is 33% of the Requirement.

JWST PMSA Error Budget
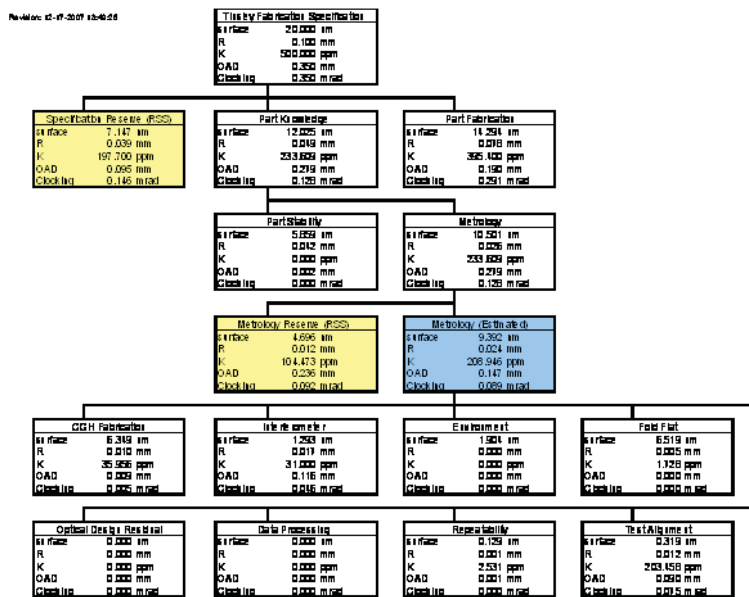
Tinsley Test Reproducibility
(OTS-1 Test #1 vs. Test #2) VC6GA294-VC6HA270

Total Surface Delta:
PV: 373 nm
RMS: 7.6 nm

Power
(Radius
Delta: 0.02
mm)

Astigmatism:
4.4 nm RMS

Mid Frequency:
4.3 nm RMS

High Frequency:
3.9 nm RMS

BATC to Tinsley Initial Comparison too large

RMS: 28.3 nm
PV: 205.4 nm

Power

Astigmatism

Mid Frequency

High Frequency

Initially, BOTS and TOTS Radius did not agree.
Discrepancy was determined to be caused by
bulk temperature difference. Agreement is now
at 10 nm rms level.

Mirror Fabrication Status
ALL DONE & DELIVERED

Spare Mirrors

Flight Mirrors

EDU
(A type)
14.9 nm-rms

C7
238 nm-rms

B1
8.0 µm-rms

SM#1
33 nm-rms

B7
22.2

C2
19.5

C1
21.5

B2
17.8

A6
44.0

B8
23.3

A3
21.0

A5
15.7

C6
23.3

PMS's

C3
17.8

A2
21.9

A4
16.8

B5
18.1

A1
17.7

B3
18.3

C5
20.1

C4
39.2

B6
17.0

SM#2
5.9 nm-rms

TM
4.3 nm-rms

FSM
2.3 nm-rms

SURFACE FIGURE ERROR
Total PM Composite: 23.2 nm RMS
PM Requirement: 25.0 nm RMS
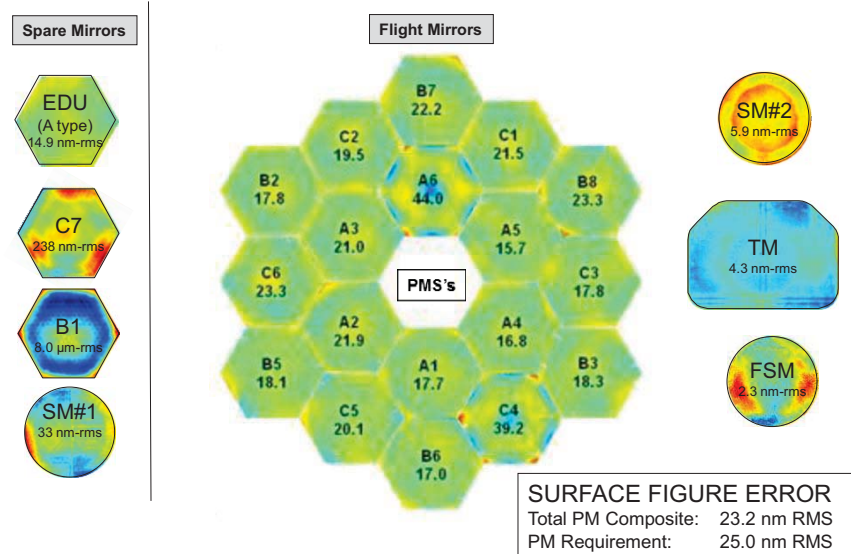
James Webb Space Telescope: large deployable cryogenic telescope in space. Lightsey, Atkinson, Clampin and Feinberg, Optical Engineering 51(1), 011003 (2012)

Develop an Error Budget

To correct way to develop an error budget is to perform a propagation of error analysis.

Start with the equation which defines how the requirement is calculated from the measured parameters.

Propagation of error connects the uncertainty of the calculated parameter to the uncertainty of the measured quantities.

$$\sigma_R = \sqrt{\left(\frac{\delta f(a,b,c)}{\delta a}\right)^2 \sigma_a^2 + \left(\frac{\delta f(a,b,c)}{\delta b}\right)^2 \sigma_b^2 + \left(\frac{\delta f(a,b,c)}{\delta c}\right)^2 \sigma_c^2}$$

Lesson Learned – validate error budget early

On ITTT program (which became Spitzer) I was SM engineer.

I had a complete error budget, but some elements were allocations.

Secondary Mirror was manufactured to a Hindle sphere test and the optician achieved an excellent result.

Unfortunately, I didn't calibrate the Hindle sphere until it was time to perform the final certification and it had a trefoil mount distortion.

Because SM had a three point mount, every time it was tested, the bumps on the SM exactly matched the holes in the Hindle sphere.

Fortunately, it still met specification; it was just not spectacular.

Moral of the story:
  Validate your error budget early, and
  As much as possible, randomize your alignment from test to test.

Sometimes bad things happen from been too meticulous. (This could almost be an 8th rule.)

Rule #3: Continuous Metrology Coverage

Third, have continuous metrology coverage:
  'you cannot make what you cannot test'
  (or 'if you can test it then you can make it').

Every step of the manufacturing process must have metrology feedback and there must be overlap between the metrology tools for a verifiable transition.

Failure to implement this rule typically results in one of two outcomes:
  very slow convergence, or
  negative convergence.

Optical Component Manufacturing Flow

Manufacturing flow is nearly identical for all optical components

BRUSH	AXSYS	TINSLEY	BALL	XRCF	BALL
• Hip Blank	• Machine Mirror Substrate	• Grind Mirror • Initial Polish Operations	• Bond flexures • Attach whiffles & surrogate delta frame • Attach ROC & hexapod	• Measure mirror cryogenically	• De-integrate actuation systems
C1	C1	C1	C1 → C2 → C3	C3	C3 → C2

TINSLEY	BALL	QCI	BALL	XRCF
• Final Polish	• Critically Clean to Flight Requirements	• Coat Mirror	• Integrate actuators • Characterize Hexapod • Acceptance Vibe	• Final acceptance test at cryogenic temperature
C2	C2	C2	C2 → C3	C3

There are Metrology 'Gates' between each processing step.
Components must meet their requirements to go to the next step.

Continuous Metrology Coverage

JWST developed overlapping tools to measure & control
   conic constant,
   radius of curvature,
   prescription alignment and surface figure error
throughout the fabrication process.

During rough grinding, used a Leitz Coordinate Measuring Machine (CMM) for radius of curvature & conic constant.

During polishing, meterololgy was provided by a Center of Curvature (CoC) interferometric test.

Leitz CMM

CMM was sized to test PMSA Full Aperture
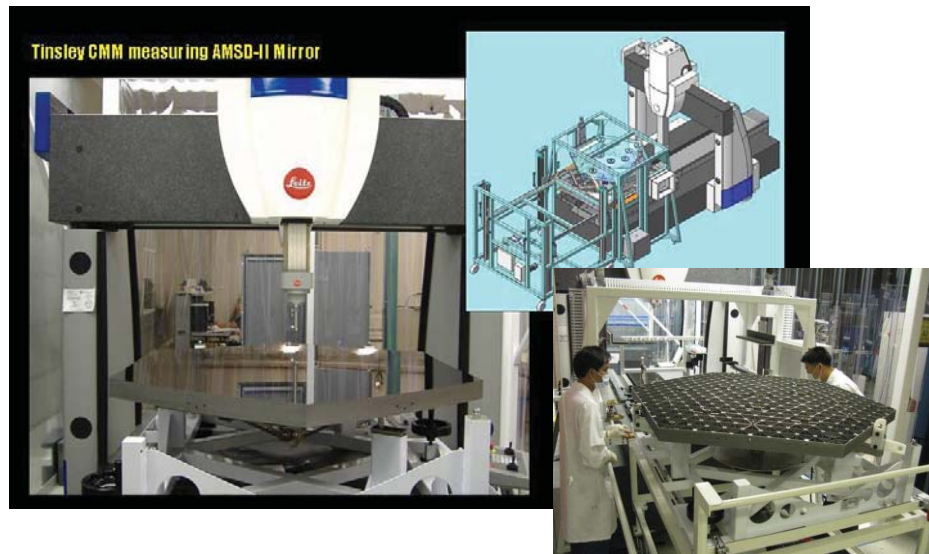
Full Aperture Optical Test Station (OTS)

Center of Curvature Null Test measured & controlled:
Prescription,
Radius &
Figure

Results are cross-checked between different 2 test stations.
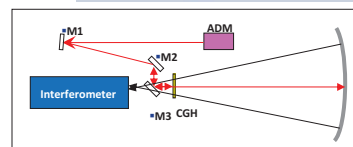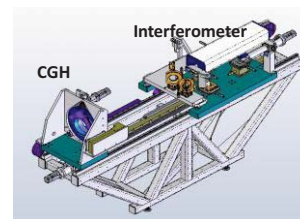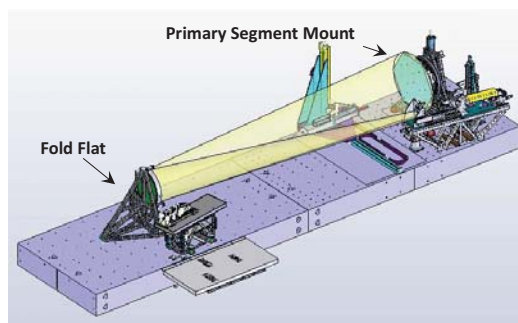
Continuous Metrology Coverage

Ordinarily, optical fabricators try to move directly from CMM to optical test during fine grinding. But, given the size of JWST PMSAs and the mid-spatial frequency specification, this was not possible.

Bridge data was provided by a Wavefront Sciences Scanning Shack Hartmann Sensor (SSHS).

Its infrared wavelength allowed it to test surfaces in a fine grind state.

And, its large dynamic range (0 to 4.6 mrad surface slope), allowed it to measure surfaces which were outside the interferometer's capture range.

Wavefront Sciences Scanning Shack-Hartmann

SSHS provided bridge-data between grind and polish, used until PMSA surface was within capture range of interferometry

SSHS provide mid-spatial frequency control: 222 mm to 2 mm

Large dynamic range (0 – 4.6 mr surface slope)

When not used, convergence rate was degraded.

8/14/2014
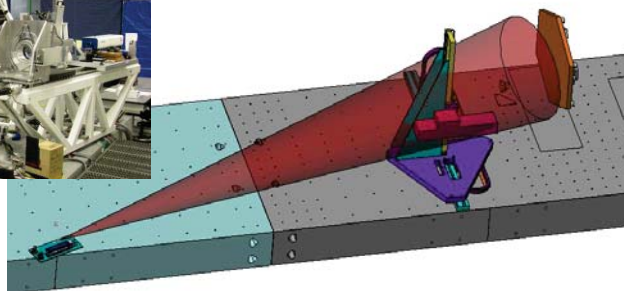
Comparison (222 - 2 mm spatial periods) 8/1/06

Smooth grind
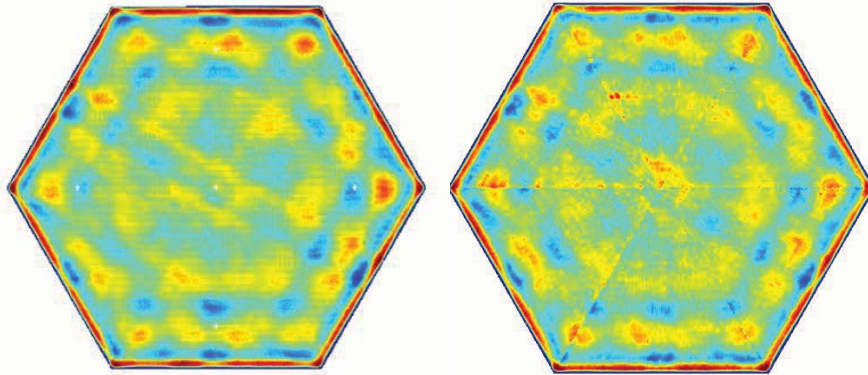
SSHS
4.7 µm PV, 0.64 µm RMS

CMM
4.8 µm PV, 0.65 µm RMS

Point-to-Point Subtraction: SSHS - CMM = 0.27 µm RMS

Rule #4: Know where you are

It might seem simple, but if you don't know where a feature is located on the mirror, you cannot correct it. This requires fiducials.

There are two types of fiducials: Data Fiducials and Distortion Fiducials.

Data fiducials are used to define a coordinate system and locate the measured data in that coordinate system. Sometimes this coordinate system is required to subtract calibration files, other times it is required to produce hit maps.

Distortion fiducials are used to map out test setup pupil distortion. Many test setups, particularly those with null optics can have radial as well as lateral pupil distortion. Distortion can cause tool mis-registration errors of 10 to 50 mm or more.

Fiducials

Fiducials can be as simple as a piece of tape or ink marks on surface under test or as sophisticated as mechanical 'fingers' protruding into clear aperture.

For computer controlled processes, fiducial positional knowledge is critical.

Because test setups might invert or flip the imaging, I highly recommend an asymmetric pattern. The pattern which I have always used is:
- 0/180 degree fiducials produce a central axis for the data set,
- 90 degree fiducial defines left/right, and
- 30 degree fiducial defines top/bottom.

For rotationally symmetric systems, one option for distortion fiducials is multiple marks along a radius.

But for asymmetric systems, a grid of marks is required.

Finally, if you have a clear aperture requirement, place marks inside and outside of the required clear aperture.

Master Datums and Fiducials

Mirrors are manufactured in Observatory Coordinate Space as defined by 'Master Datums' on back of each mirror substrate.

Figure error is measured using 'Data Fiducials' on front of each mirror which are registered to 'Transfer Fiducials' (tooling balls) on the side of each mirror.
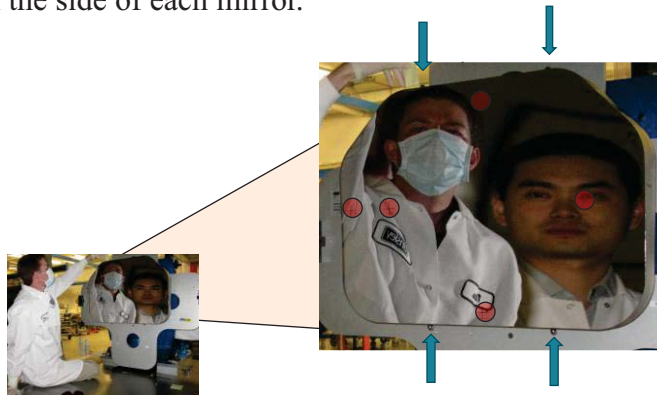
Master Datums and Fiducials

Data, Distortion and Edge Fiducials are used for PMSA testing.

Transfer Fiducials register these to the Master Datums on back.

This knowledge is critical because of redundancy between alignment
errors and surface figure errors
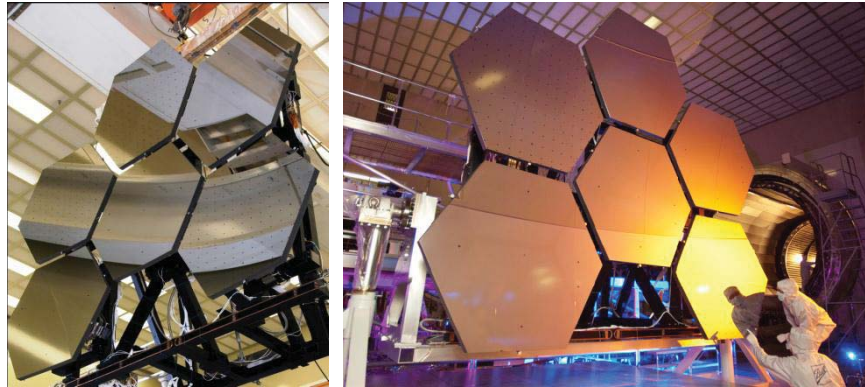
Lesson Learned

Another problem is software coordinate convention.

Most interferometer analysis software assumes that the optical (Z
axis) positive direction points from the surface under test
towards the interferometer, such that a feature which is higher
than desired is positive.

But, many optical design programs define the positive optical
axis to be into the surface.

The problem occurs because both programs will typically define
the Y-axis as being up, so it is critical to understand which
direction is +X-axis.   (I have actually seen a software program
which used a left handed coordinate system)

The problem is further complicated when interfacing with the
optical shop. You must know the coordinate system of every
computer controlled grinding and polishing machine.

Rule #5: 'Test like you fly'

You must 'Test like you fly'.

JWST operates in the cold of space. Therefore, we must certify
  30K optical performance in the MSFC XRCF, and
  'zero-g' performance via a 6 rotation test at BATC BOTS.

Observatory level qualification < 50K is done at JSC Chamber A.

Also, 'test as you fly' is not limited to space telescopes. Ground based telescopes can have large gravity sags.

  Therefore, they must be tested in their final structure (or a surrogate).

PMSA Flight Mirror Testing at MSFC XRCF

Cryogenic Performance Specifications are Certified at XRCF

Because JWST mirrors are fabricated at room temperature (300K) but operate < 50K, their shape change from 300 K to 30K is measured to generate a 'hit-map', and cryo-null polish the mirrors.
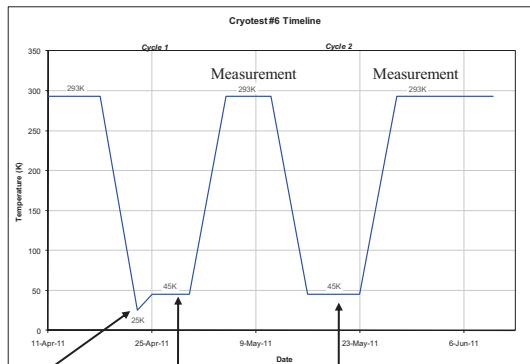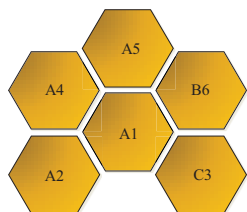

Cryo-Vacuum Chamber is 7 m dia x 23 m long
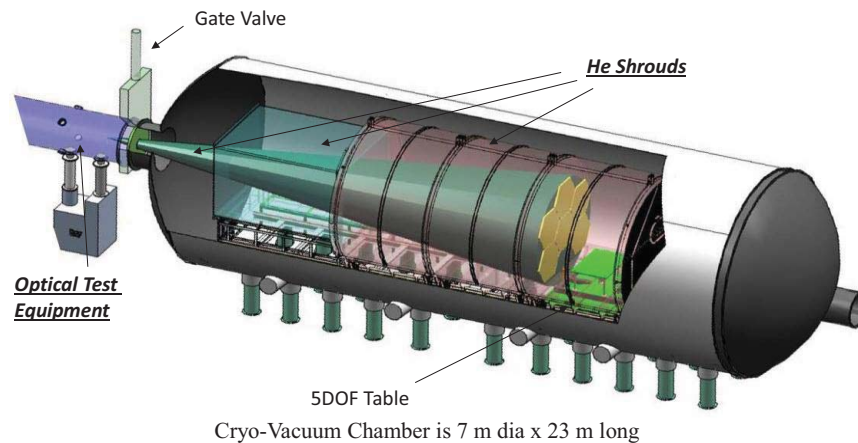
JWST Flight Mirror Test Configuration
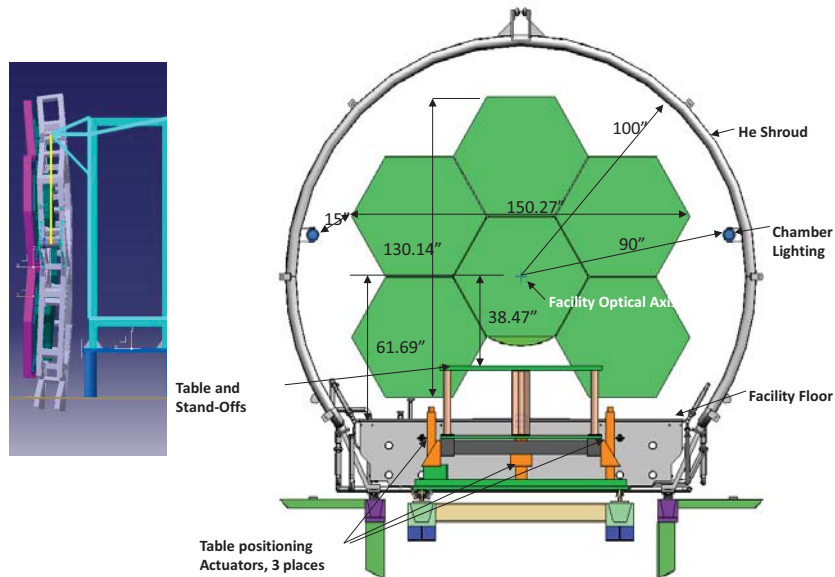
Primary Mirror Cryogenic Tests

XRCF Cryo Test
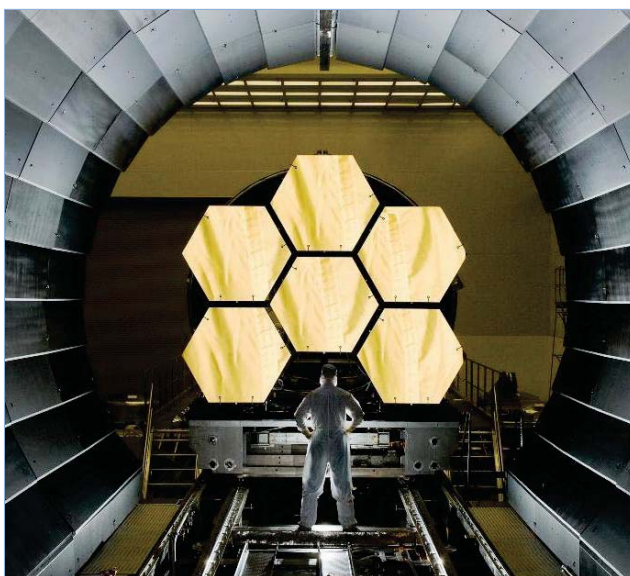

Cryotest #6 Timeline
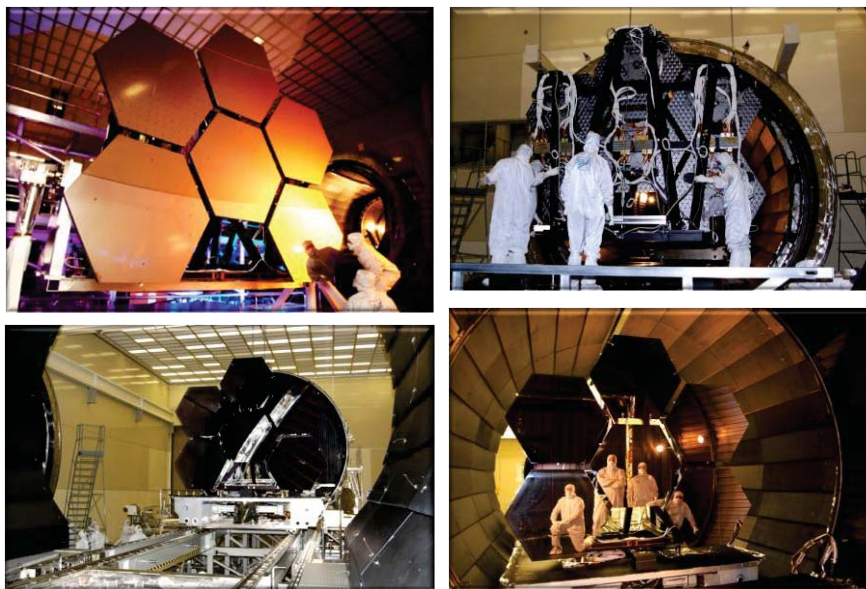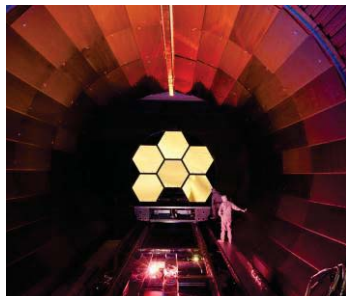
- Survival Temperature
- Cryo Deployment
- Nominal Measurement
- Hexapod Deformation Pose
- RoC Actuation Test
- Hexapod Envelope Test
- Pullout Current & Redundant Test (3 of 6 PMSAs)
- Set RoC
- Nominal Measurement
- Hexapod Tilt Test
- Pullout Current & Redundant Test (3 of 6 PMSAs)

Flight Mirrors in XRCF

Lesson Learned

While Gravity is a significant problem for large mirrors.

It is also problem for lightweight mirrors in non-kinematic mounts

Once I had a task to test an 'egg-crate' 0.75 meter diameter flat mirror to 30 nm PV.

After initial characterization tests with the customer, I declined.

The customer provided 'metrology' mount was unsuitable.

The mirror was so 'floppy' (i.e. low stiffness) that simply picking it up and setting it back down onto the metrology mount resulted in a 100 nm PV shape change (both astigmatic bending and local mount stress).

Rule #6: Independent Cross-Checks

Probably the single most 'famous' lesson learned from Hubble is to never rely on a single test to certify a flight specification.

Every JWST optical component specification had a primary certification test and a confirming test.

Every Requirement has an Independent Validation

Parameter	Spec	Tol	Units	Verification	Validation
Clear Aperture (Edge Specification)	1.4776 (5)	Min (Max)	mm^2 (mm)	Measure edges at ambient using Tinsley HS Interferometer	Measure area at cryo using XRCF CoC Interferometer
Scratch-Dig	80-50	Max		Ambient Visual Inspection	Independent Visual
Conic Constant	-0.99666	+/- 0.0005		Measured at cryo and defined by null geometry for XRCF CGH CoC test	Ambient test at Tinsley, compare CGH CoC test with auto-collimation test
Radius of Curvature	*	+/- 0.15	mm	Set at XRCF using ADM	ROCO Comparison
Prescription Alignment Error					
Decenter	*	≤ 0.35	mm	Cryogenic test at XRCF, defined by residual wavefront error relative to CGH CoC test and fiducial alignment	Ambient test at Tinsley, compare CGH CoC test with auto-collimation test
Clocking	0	≤ 0.35	mrad		
Piston	N/A			Ambient CMM measurement at AXSYS	Ambient CMM measurement at Tinsley
Tilt	N/A				
Total Surface Figure Error:					
Low/Mid Frequency	20	Max	nm rms	Cryo-Test at XRCF	Cryo-Test at JSC
High Frequency	7	Max	nm rms		
Surface Roughness	4	Max	nm rms	Ambient Chapman measurement at Tinsley	NONE

Ball Optical Test Station (BOTS)

Tinsley ambient metrology results are 'cross-checked' at BATC BOTS measurements:

- Measure Configuration 1 to 2 deformation
- Measure Configuration 2 to 3 deformation
- Create a Gravity Backout file for use at XRCF
- Measure Vibration Testing Deformation
- Measure Vacuum Bakeout Deformation
- Measure Configuration 2 mirrors for BATC to Tinsley Data Correlation

Interferometer   Environmental Enclosure   6 DOF Test Stand and Mirror
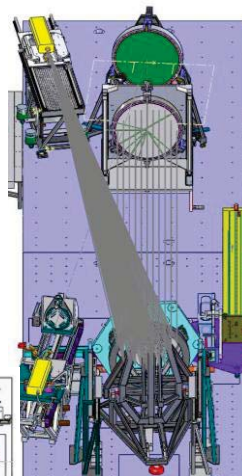
CGH   Enclosure Door
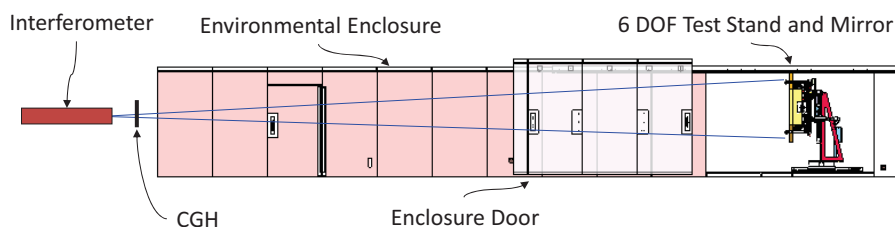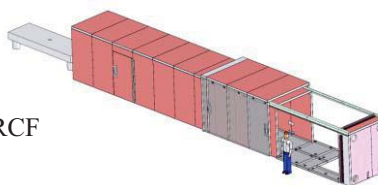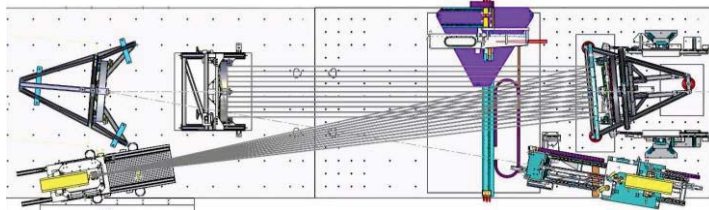
Auto-Collimation Test

Auto-Collimation Test provides independent
cross-check of CGH Center of Curvature Test

Verifies:

Radius of Curvature

Conic Constant

Off-Axis Distance

Clocking

Note: is not a full-aperture figure verification test

Final Cross-Check performed at Observatory Level

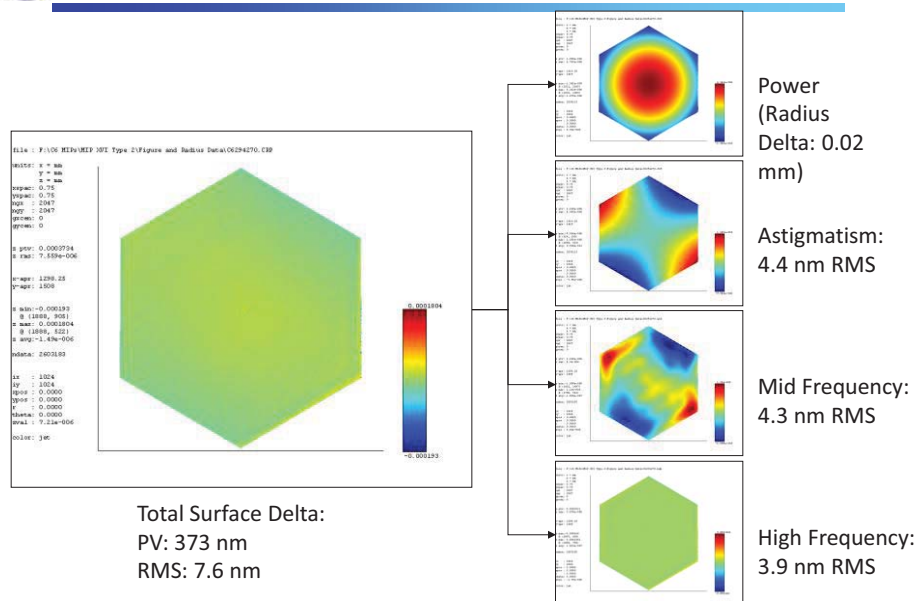| Johnson Space Center Chamber A	
Chamber size	16.7 meter diameter, 35.6 meter tall
Existing Shrouds	LN2 shroud, GHe panels
Chamber Cranes	4 x 7.6 meter fixed, removable
Chamber Door	12 meter diameter
High bay space	~31 m L x 21.6 m W
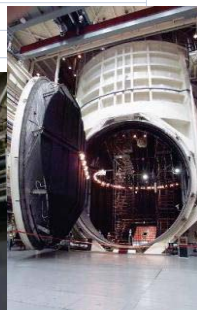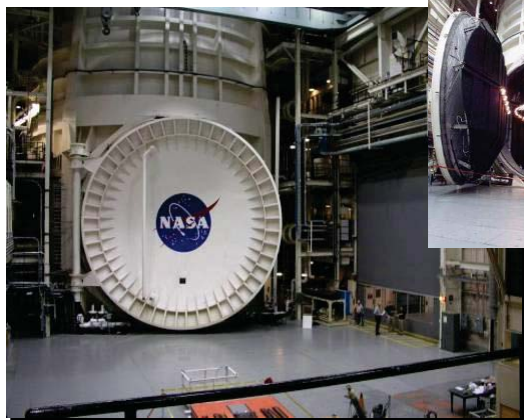
Rule #7: Understand All Anomalies

Of all the rules, this one maybe the most important and must be followed with independent rigor.

No matter how small, one must resist the temptation of sweeping a discrepancy under the metaphorical error budget rug.
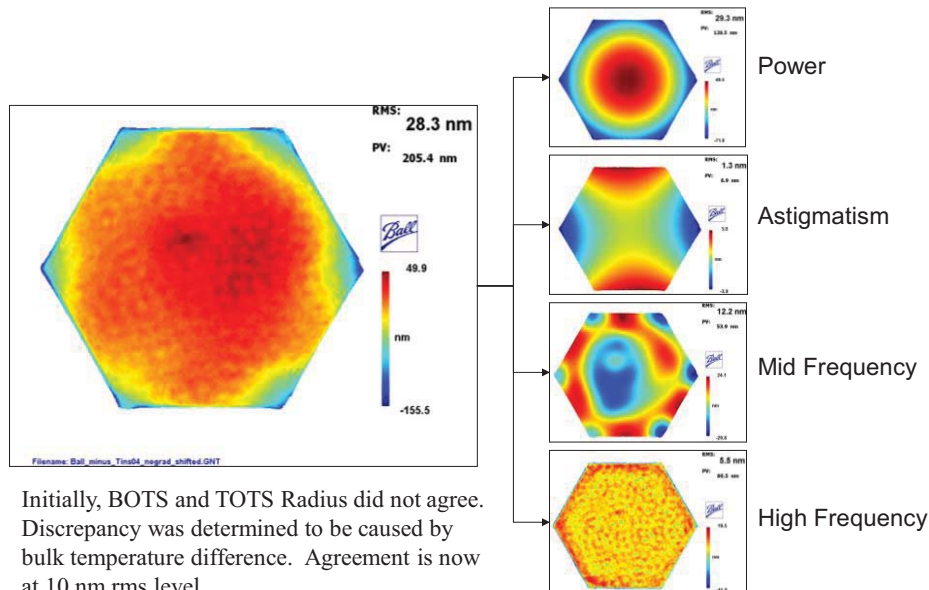
Tinsley Test Reproducibility
(OTS-1 Test #1 vs. Test #2) VC6GA294-VC6HA270

Total Surface Delta:
PV: 373 nm
RMS: 7.6 nm

Power (Radius Delta: 0.02 mm)

Astigmatism: 4.4 nm RMS

Mid Frequency: 4.3 nm RMS

High Frequency: 3.9 nm RMS

BATC to Tinsley Initial Comparison too large

RMS:
28.3 nm

PV:
205.4 nm

nm

49.9

-155.5

Filename: Ball_minus_Tins04_negrad_shifted.GNT

Initially, BOTS and TOTS Radius did not agree.
Discrepancy was determined to be caused by
bulk temperature difference. Agreement is now
at 10 nm rms level.

Power

Astigmatism
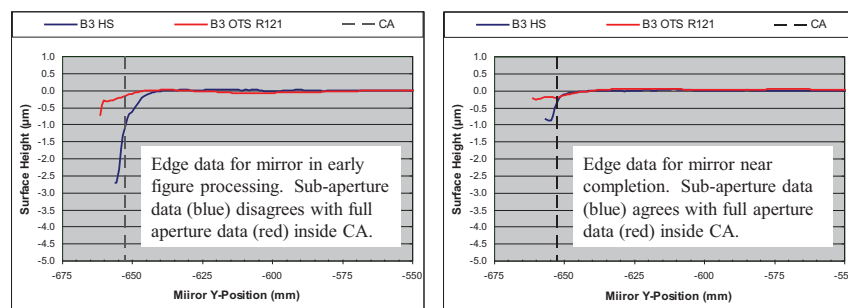
Mid Frequency

High Frequency

Lesson Learned: Clear Aperture Edge Specification

Center of Curvature test and High-Spatial Frequency test gave
entirely different answers for compliance with Edge
Requirement – 15 mm difference.

Which one was right had significant cost & schedule impact.

HS was right, CoC was wrong.

Problem was caused by depth of focus and Fresnel diffraction.

Edge data for mirror in early figure processing. Sub-aperture data (blue) disagrees with full aperture data (red) inside CA.

Edge data for mirror near completion. Sub-aperture data (blue) agrees with full aperture data (red) inside CA.

Conclusions

Based on 30 years of optical testing experience, I have defined seven guiding principles for optical testing.
- Fully Understand the Task
- Develop an Error Budget
- Continuous Metrology Coverage
- Know where you are
- 'Test like you fly'
- Independent Cross-Checks
- Understand All Anomalies

With maybe an 8th of deliberately disturbing or randomizing the test.

JWST optical component in-process optical testing and cryogenic compliance certification, verification & validation was accomplished by a dedicated metrology team used these principles.

All JWST optical components meet their requirements.